

Ralchenko Viktor G.

Course Schedule

WEDNESDAY

11:55 – 13:30	■ LEC	Plasma Cvd of Thin-film Structures (2017-03-01 – 2017-03-15)	👥 M15-305, M15-306	📍 FIAN
	■ SEM	Plasma Cvd of Thin-film Structures (2017-03-22 – 2017-04-05)	👥 M15-305, M15-306	📍 FIAN
13:35 – 17:00	■ SEM	Plasma Cvd of Thin-film Structures	👥 M15-305, M15-306	📍 FIAN